



EFW

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Fuminori HAYANO

Group Art Unit: 2877

Application No.: 10/760,586

Examiner: I. AKANBI

Filed: January 21, 2004

Docket No.: 117681

For: METHOD AND APPARATUS FOR MEASURING OPTICAL OVERLAY
DEVIATION

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the February 9, 2006 Office Action, please consider the following:

Amendments to the Specification; and

Remarks.